

AMENDMENT TO THE CLAIMS

1. (original): A method for automated focusing of an electron image, the method comprising:
 - determining an energy filter cut-off voltage; and
 - adjusting a focusing condition in compensation for a change in the energy-filter cut-off voltage.
2. (original): The method of claim 1, further comprising:
 - varying an energy filter voltage to different levels;
 - measuring an intensity of detected electrons at each of the different levels; and
 - analyzing the intensity data so as to determine the energy filter cut-off voltage.
3. (original): The method of claim 1, wherein the focusing condition comprises a wafer bias voltage, and wherein the wafer bias voltage is varied in correspondence to the change in the energy filter cut-off voltage.
4. (original): The method of claim 1, wherein the focusing condition comprises an objective lens focusing strength.
5. (original): The method of claim 1, wherein the focusing condition comprises an extraction field strength.
6. (original): The method of claim 1, wherein the focusing condition comprises a source voltage level.
7. (original): The method of claim 1, further comprising using a contrast-based focusing procedure for fine focusing of the electron image.
8. (cancelled):
9. (cancelled):

10. (cancelled):

11. (original): A electron beam inspection apparatus, the apparatus including an autofocusing means that comprises:

means for determining an energy filter cut-off voltage; and

means for adjusting a focusing condition in compensation for a change in the energy-filter cut-off voltage.

12. (cancelled)

13. (cancelled)

14. (cancelled)

15. (cancelled)

16. (cancelled)

17. (cancelled)

18. (cancelled):

19. (cancelled):

20. (cancelled):

21. (cancelled):

22. (cancelled)

23. (cancelled):